

MSW '02 > Background > MSW '98

MSW '98**MARCH 24, 1998**

8.15-9.00	<i>Registration</i>	
9.00	Introduction	
9.10	Wind, sound, smell, and intrusion detected by micromachined thermal CMOS sensors (Invited)	Henry Baltes, Oliver Brand and Andreas Koll (ETH Zürich, Switzerland)
9.55	Medical applications of microsystems	J. Malcolm Wilkinson and David Hitchings (Technology For Industry Ltd, Great Britain)
10.15	NORMIC - Nordic Microsystems Manufacturing	Stein Ivar Hansen (SensoNor), Edvard Kälvesten (IMC), Joan Bausells (CNM), Ralph W. Bernstein (Sintef), Jaako Salonen (VTT) and Ole Steensen (MIC)
10.35	<i>Break</i>	
11.05	Microprocessing - an armchair approach (in Swedish)	Greger Thornell and Stefan Johansson (Uppsala Univ.)
11.30	Bonded wafers for use in MEMS manufacturing	Karin Hermansson and Scott Blackstone (BCO Technologies, Great Britain)
11.50	Research of permanent magnet microfabrication technology and electromagnetic microdevices at Tallinn Technical University	Arvi Kruusing and Vitali Podgurski (Tallinn Technical Univ., Estland) (Uppsala University)
12.10	Three dimensional microstructures based on polyimide joints	Thorbjörn Ebefors, Edvard Kälvesten, Johan Mattsson and Göran Stemme (KTH)
12.30	<i>Lunch</i>	

13.30	Novel SPM probes - fabrication and characterization (Invited)	Anja Boisen (MIC, Denmark)
14.20	Creation and development of latent microstructures (in Swedish)	Greger Thornell and Klas Hjort (Uppsala Univ.)
14.40	Further development of an electron tunneling accelerometer	Patrick Scheeper (Brüel & Kjær, Denmark)
15.00	<i>Break</i>	
15.30	Micro propulsion thrusters for space applications	Mats Jönsson, Johan Köhler, Kajsa Larsson, Urban Simu (Uppsala Univ.), Lars Stenmark (ACR Electronic)
15.50	A shear mode piezo printhead - manufactured in Sweden	Gerhard Beurer (Modular Ink Technology), Joachim Kretschmer (Pelikan Produktions AG)
16.10	Micro fluidic components in diamond	Henrik Björkman, Pelle Rangsten, Urban Simu, Joakim Karlsson, Patrik Hollman and Klas Hjort (Uppsala Univ.)
16.30	MST at Industrial Microelectronics Center (in Swedish)	Christian Veider (IMC)
17.00	Poster presentations	
17.15	Poster session with refreshments Posters listed alphabetically: - Encapsulation of silicon resonant structures Corman, Enoksson, Stemme (KTH) - Fabrication of a micro-electromagnet Larsson, Boman (Uppsala Univ.) - Flow-through piezo-electric picoliter dispenser Nilsson, Laurell, Wallman, Nilsson, Johansson (LTH) - IMC - Industriellt MikroelektronikCentrum Veider et al (IMC) - Micro Structure Technology at the Ångström Laboratory (Uppsala Univ.) - Optically excited microresonator for force measurements Johansson, Sohlström, Enoksson, Stemme (KTH) - Packaging of micromachined components	

	<p>Rusanen (VTT Electronics, Finland)</p> <ul style="list-style-type: none"> - Polymer microactuators for cell biology and nanoliter chemistry <li style="padding-left: 20px;">Jager, Inganäs, Lundström (Linköpings Univ.), Smela (Risø National Lab.) - Progress update on gyro industrialization <li style="padding-left: 20px;">Söderkvist (Colibri Pro Development) - Sensors and microsystems at Chalmers <li style="padding-left: 20px;">Malmquist, Weinert, Westberg, Andersson (Chalmers) - Some recent advances in micromachining technology <li style="padding-left: 20px;">Thornell, Johansson (Uppsala Univ.) - Tallinn Technical University <li style="padding-left: 20px;">Kruusing et al (Tallinn Technical Univ., Estonia) - The many faces of MITE <li style="padding-left: 20px;">Thornell et al (Uppsala Univ.)
18.30	<i>Dinner</i>

MARCH 25, 1998

8.45	Simulations - a tool that opens design possibilities	Jan Söderkvist (Colibri Pro Development)
9.00	Laser to fiber alignment using microstructured silicon carriers	Bernt Sundström (Ericsson Components), Henrik Åhlfeldt, Johan Holm, Stefan Lindgren, Christian Vieider (IMC)
9.20	A large micromachined resonant scanning mirror (in Swedish)	Mattias Vangbo, Staffan Karlsson and Ylva Bäcklund (Uppsala Univ.)
9.40	An optical IR-source and CO ₂ -chamber system for CO ₂ measurements	Edvard Kälvesten, Thierry Corman, Göran Stemme (KTH), Matti Huiku, Pekka Meriläinen (Datex-Engström, Finland)
10.00	InP based micro opto electro mechanics	Donato Pasquariello, Mikael Karlsson, Staffan Greek and Klas Hjort (Uppsala Univ.)
10.20	<i>Break</i>	
10.50	From research lab to MEMS fab: case Vaisala - VTI Hamlin (invited)	Heikki Kuisma (VTI Hamlin Oy, Finland)
11.40	Surface micromachined pressure sensors for	Edvard Kälvesten, Göran Stemme (KTH), Leif

	cardiovascular pressure measurements	Smith, Lars Tenerz (Radi Medical Systems)
12.00	Is the MEMS-commercialization micromachining or system-driven	Jan Söderkvist (Colibri Pro Development)
12.15	<i>Open discussion on industrialization issues</i>	
12.25	<i>Lunch</i>	
13.25	Lilliputian reflections (in Swedish)	Greger Thornell (Uppsala Univ.)
13.45	A low impedance sensing technique for vibrating structures	Anke Weinert, Mats Berggren and Gert I. Andersson (Chalmers)
14.05	Polymer microactuators for cell biology and nanoliter chemistry	Edwin W. Jager, Olle Inganäs, Ingemar Lundström (Linköpings Univ.), Elisabeth Smela (Risø National Lab.)
14.25	Miniaturized X-ray sources	Leif Smith (Radi Medical Systems)
14.45	Update on Summit and AME	Jan-Åke Schweitz (Uppsala Univ.)
15.15	<i>Break</i>	
15.45-~16.30	Tour of the Ångström Laboratory	Ylva Bäcklund (Uppsala Univ.)